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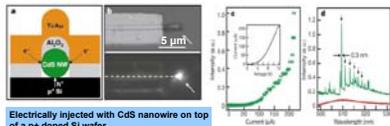
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Introduction: Semiconductor nanowires (NWs) have attracted a great attention in various fields of technology due to their size and hence enhanced properties. III-V NWs have proven their potential in fabrication and property improvement of various devices such as nano-sized laser diodes, light emitting diodes, high electron mobility devices, single photon source, solar cells and biological sensors.^{1,2,3} Growth of radial and axial heterostructured III-V NWs by molecular beam epitaxy (MBE) using the Au-assisted vapor-liquid-solid mechanism has been reported.⁴ However, MBE-grown III-V NWs normally assume a wurtzite (WZ) crystalline structure often suffered by stacking faults compared to that of zinc blende (ZB) crystalline structure in its bulk form.⁵ These stacking faults may be a detrimental problem for optical device applications using NWs. In this study, we show a method of controlling the stacking faults in the GaAs NWs.

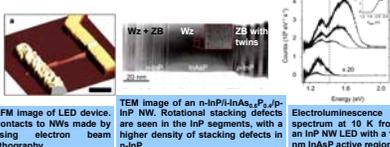
1. Nanowire based devices:

1. Single-nanowire electrically driven lasers²



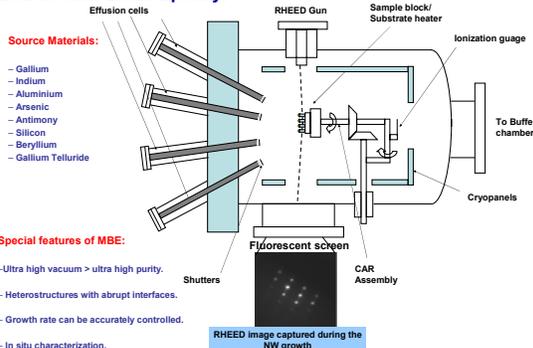
- Very crude design (not heterostructured, no in built p-n junction).
- Very poor performance.

2. Single quantum dot Light emitting diodes³

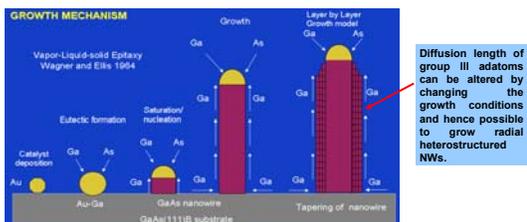


- High density of stacking faults.
- No radial heterostructures.

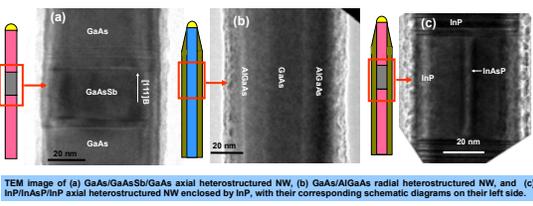
2. Molecular Beam Epitaxy:



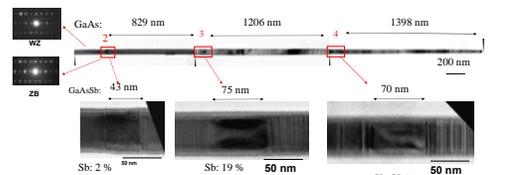
3. Nanowire growth mechanism:



4. Heterostructured nanowires:

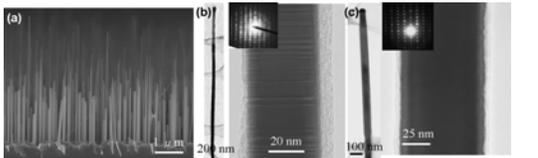


5. GaAs/GaAsSb axial heterostructured nanowires:



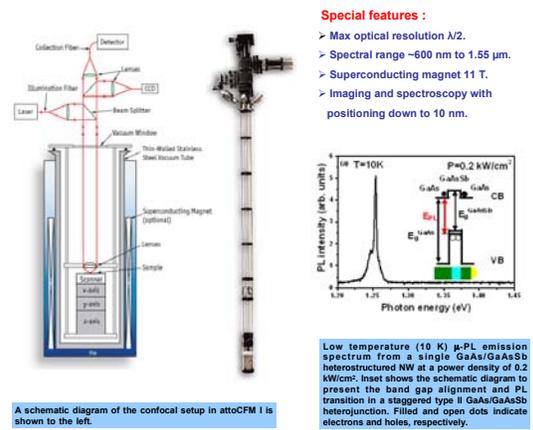
High resolution TEM image of a GaAs NWs with GaAsSb inserts. The growth rate of NW and density of stacking faults is observed to vary along the length of the GaAs NW. We attribute the formation of stacking faults to the faster growth rate of NWs.

6. Defect-free GaAs nanowires :



(a) Cross sectional view SEM image of GaAs NWs showing long and short NWs. (b) Overview image of long NW (b) and short NW (c) with their corresponding high resolution TEM images and SAED patterns in the insets. This indicates that stacking faults can be controlled by decreasing the growth rate of NWs.

7. Our new approach : Low temp. (2K) scanning confocal microscope with magnet :



8. Results & Conclusions:

1. We could grow axial and radial heterostructured NWs successfully.
2. We demonstrate the technique to grow defect-free WZ GaAs NWs by MBE.

References:

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Acknowledgements:

Part of this work was supported by the NANOMAT program (Grant no. 182091) and the Norwegian-French "AURORA" program (Grant no. 187692) of the Research Council of Norway.